

Bromine Etching of Patterned $\text{YBa}_2\text{Cu}_3\text{O}_{6+x}$ Nanoscale Thin Films for High-Temperature Superconducting Devices

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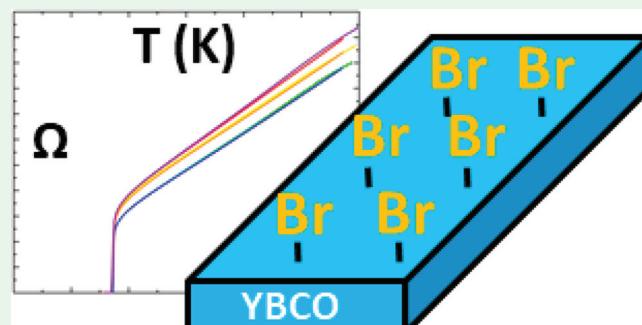
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ABSTRACT: Cuprate high-temperature superconducting (HTS) thin films like $\text{YBa}_2\text{Cu}_3\text{O}_{6+x}$ (YBCO) are subject to reduction reactions with CO_2 and H_2O . This poses a challenge for processing and storing nanoscale devices made from these films. A 1% bromine–ethanol etchant solution was investigated as a facile processing method for thin 50 nm films of patterned YBCO. Raman scattering, EDS, AFM, and HIM imaging show changes in the surface morphology and composition. RT measurements show electrical changes to a depth of ~ 3 nm after bromination and a slight reduction in T_c (86.5 to 86.4 K). We conclude that bromination of YBCO has minimal electrical consequences.

KEYWORDS: YBCO, superconductor, bromine, etching, nanoscale devices



High-temperature superconductivity was arguably one of the most exciting discoveries of the 20th century. The ceramic cuprate $\text{YBa}_2\text{Cu}_3\text{O}_{6+x}$ (YBCO) is one of the most popular high-temperature superconducting (HTS) materials, the thin films of which are used in variety of applications such as qubits in quantum computing,¹ analog to digital converters,² neuromorphic circuits,³ and innumerable others. This HTS material boasts a critical temperature (T_c) of 93 K⁴ making superconducting devices more practical for consumer applications, as they can be cooled by liquid nitrogen (which has a boiling temperature of 77 K) instead of expensive liquid helium (which boils close to absolute zero at 4 K).

When used in devices such as Josephson junctions (JJs), the comprising superconducting thin films have thicknesses on the order of 20–200 nm.⁵ New methods of JJ fabrication, such as Focused helium ion beam (FIB) technology, require even tighter thickness parameters, on the order of tens of nanometers, as the depth of beam penetration is dependent on the beam energy. The rate of environmental degradation is proportional to decreasing film thickness.⁶ This creates urgency for new nanoscale-friendly processing for upcoming generations of fabricated devices, as thinner films are subject to faster rates environmental degradation because of an increased surface-area-to-volume-ratio.

The chemistry of YBCO degradation can be explained by reduction reactions with molecules in the air such as CO_2 and H_2O ⁷ depleting the saturation of oxygen within the crystal and leading to poorer electronic device performance, such as lowering T_c . In YBCO, electronic properties (and particularly the T_c) are variable and depend on the concentration of oxygen within the crystal lattice as it deviates from 6 to 7 mol

per formula unit. Below a mole ratio of 6.2 O/f.u., superconductivity is completely destroyed as the material changes from a superconducting orthorhombic crystal structure to an insulating tetragonal unit cell.⁸ Therefore, protecting YBCO and its precious high oxygen concentration presents challenges in the storage of YBCO-based devices such as JJs without compromising their superconducting performance.

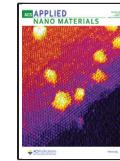
From an electronic perspective, protecting this material from the environment poses a unique challenge for nanoscale devices. First, the superconducting state is facilitated by the mixed 2^+ and 3^+ oxidation states of copper atoms within the material. In turn, these oxidation states are linked to the concentration of oxygen. This is contradictory to most other passivation endeavors: YBCO must maintain oxidation, while traditional methods aim to prevent oxidation. Additionally, device processing methods must not interfere with their electrical performance, avoiding pitfalls such as lowering T_c or introducing 1/f noise into magnetic measurements from molecular surface adsorption.

To this effort, previous methods of surface passivation for YBCO have been numerous and diverse, with several approaches purposefully damaging the surface of the film to

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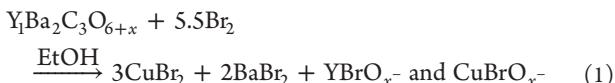
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protect the remaining HTS film underneath.^{9,10} Other methods use a variety of coatings, including metal,¹¹ oxide,⁷ carbon,¹² and polymer coatings,¹³ with some success for various applications. However, in order for this process to be optimized for nanoscale device fabrication, the method must avoid difficult processing, lattice mismatch (resulting in poor thermal cycling of the devices), the diffusion of metal ions into and out of the YBCO itself, and the diffusion of CO₂ and H₂O molecules through the coating. The majority of these studies have focused on bulk material or thick films (>100 nm), and are unexplored for nanoscale thin films. Furthermore, bromine is gaining popularity as both an etchant^{14,15} and a passivation method for solar cells,^{16,17} nanocrystals,¹⁸ and silicon wafers.¹⁹

In this study, the chemical reagent bromine has been studied as a facile means of processing HTS cuprate surfaces without altering the electrical properties of the thin films. This study performed Br–surface reactions on 50 nm thick YBCO thin films. We expect the film to form several reaction products: copper(II) bromide, barium dibromide, and yttrium–bromide–oxygen complexes attached to the film's surface. This reaction can be found in eq 1.



Here, we investigate the effects of this product formation on the electrical properties of the 50 nm thin films as a foundation for future work with nanoscale electronics. Work by Lamine Mohamed Kollakoye Dieng proposed that bromine does not enter to YBCO lattice, but rather forms nanoclusters of lattice fragments of Br–O(4)–Ba–Cu(1)Cu(2) chains.²⁰ It is these surface interactions that are of interest to thin films and nanoelectronics, possibly serving as a means to maintain the oxygen content of the greater lattice in the film.

The films used in this study were patterned with a gold circuit via photolithography, the pattern of which and resulting device can found in Figure 1. The lingering products of the

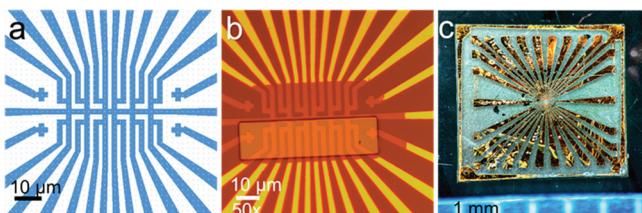


Figure 1. (a) Photolithography pattern, (b) patterned device circuitry, and (c) full chip after bromination, scale bar 1 mm.

reaction and the electrical consequences have been measured through Raman scattering, helium ion microscope (HIM) imaging, energy-dispersive X-ray spectroscopy (EDS), atomic force microscopy (AFM), and resistance–temperature (RT) measurements. This experiment allows us to precisely measure the electrical changes in the material after passivation in terms of electrical thickness, T_c , and residual resistivity.

Nanoscale images were taken of both surfaces via helium ion microscope (HIM) and atomic force microscopy (AFM). HIM images were taken of two patterned YBCO surfaces, one with bromine treatment and one without, and are shown in Figure 2. These images show the impact of bromine treatment on the YBCO surface. After treatment, the surface appears to be much more rough, with many inclusions when compared to the

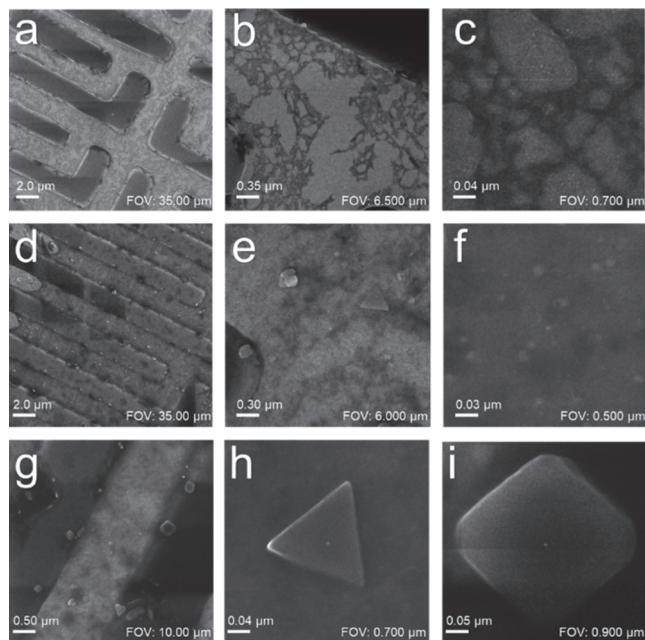


Figure 2. HIM images of the YBCO surface before (top) and after (middle) bromination at (a) 35.00, (b) 0.35, (c) 0.700, (d) 35.00, (e) 6.00, (f) 0.500 μm FOV. Images of crystalline shapes appearing on the surface of the brominated sample (bottom) with (g) many inclusions at 10.00 μm, (h) a triangular inclusion at 0.700 μm, and (i) a rhombic inclusion at 0.900 μm FOV.

untreated sample. Here, we observe several products on the order of hundreds of nanometers in scale that are stuck to the YBCO surface.

To further show the change in surface roughness, we took atomic force microscopy (AFM) images as shown in Figure 3. The top images show an identically fabricated patterned film and the bottom images show the film after bromine processing. From left to right, Figure 3a and c shows the samples via height sensing and Figure 3b and d shows the films via magnetic sensing. From these images, we can see a dramatic change in

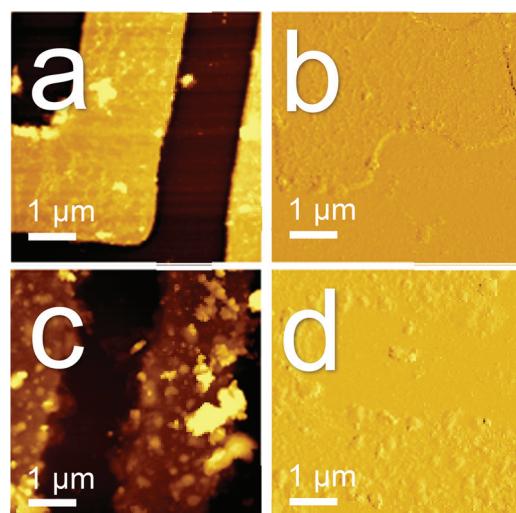


Figure 3. AFM images of (a, c) height profiles and (b, d) magnetic profiles of (a, b) unbrominated and (c, d) brominated patterned YBCO.

the surface morphology after the bromination process and an overall increase in surface roughness after treatment.

Compositional analysis to confirm the presence of bromine on the surface was done via Raman spectroscopy and energy-dispersive X-ray spectroscopy (EDS). The expected reaction products were taken from Vasquez et al. as well as Mukhopadhyay and Wei. Using photoelectron X-ray spectroscopy (XPS), they report products of YBr_3 , BaBr_3 , and CuBr in 1:4:3 product ratios²¹ and YBr_3 , YBrO_3 complexes, and electronic restructuring of Ba^{2+} and Cu^{2+} ions,²² respectively. With these products in mind, Raman spectroscopy was performed on both unbrominated and brominated samples. Figure 4 shows a Raman spectra taken from 100 to 750 cm^{-1}

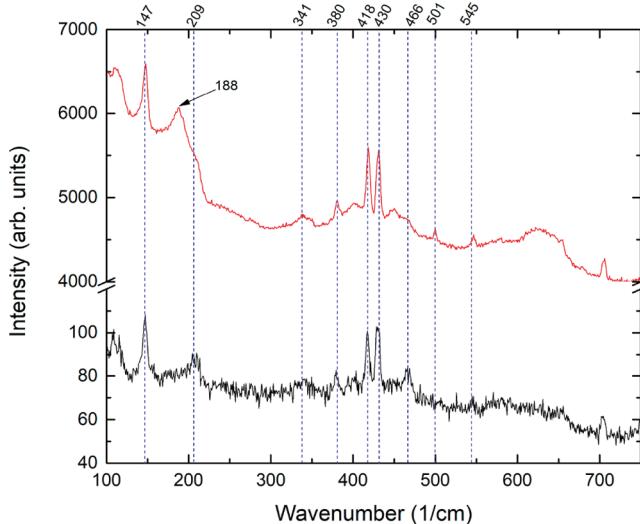


Figure 4. Raman spectra of YBCO on a sapphire substrate from 100 to 750 cm^{-1} . The black line represents an unbrominated sample and the red represents a brominated sample.

of characteristic YBCO peaks for the brominated (red) and unbrominated (black) samples. Comparing the two spectra, historically identifiable shared peaks are as follows: $\sim 147\text{ cm}^{-1}$, which has been reported to be a Cu-B_{2g} vibration,²³ likely within the YBCO structure and its environmental reduction reaction products but shifted by $\sim 2\text{ cm}^{-1}$ from the original 1992 study. The peak at $\sim 209\text{ cm}^{-1}$, which has been reported to be a $\text{O}(4)$ B_{2g} vibration inside of YBCO;²⁴ and $\sim 340\text{ cm}^{-1}$ has been reported by several authors to be an $\text{O}(2,3)$ - B_{1g} vibration.²⁵ Peaks at ~ 380 , ~ 418 , and $\sim 430\text{ cm}^{-1}$ have been identified by Lorenz et al. to arise from the sapphire substrate supporting the YBCO thin film.²⁶ At $\sim 466\text{ cm}^{-1}$, an $\sim 2\text{ cm}^{-1}$ shift occurs between the unbrominated (466 cm^{-1}) and brominated (467 cm^{-1}) samples. Both of these samples show a shift from the literature data, which present a peak characteristic of tetragonal-phase YBCO at $\sim 463\text{ cm}^{-1}$.²⁵ A theoretical peak reported by Thomsen et al. reports an $\text{O}(2,3)$ - B_{3g} vibration at 544 cm^{-1} , which is seen in this spectra at $\sim 545\text{ cm}^{-1}$ in the unbrominated spectrum and shift to $\sim 547\text{ cm}^{-1}$ in the brominated sample.²⁷

Peaks shown in both spectra at ~ 109 , ~ 403 , and $\sim 704\text{ cm}^{-1}$ have not been identified and require further study. Peaks that were not seen in the unbrominated sample but that appear in the brominated sample include in this spectra peaks at ~ 188 , ~ 501 , and $\sim 627\text{ cm}^{-1}$. The first of these peaks may be evidence of reaction product remaining on the surface after the

ethanol wash. Stepakova et. al reports a copper(II) bromide (CuBr_2) peak at $\sim 189\text{ cm}^{-1}$.²³ The second peak can be identified as an $\text{O}(4)$ - A_g apex oxygen peak at $\sim 500\text{ cm}^{-1}$.²⁴ The collection of peaks centered around $\sim 627\text{ cm}^{-1}$ take the same shape as those reported by Zhang et al. but are shifted from $\sim 540\text{ cm}^{-1}$. This could be due to the difference in film thickness.

Figure 5 shows unbrominated and brominated Raman spectra taken from 2300 to 2500 cm^{-1} . Although the Raman of

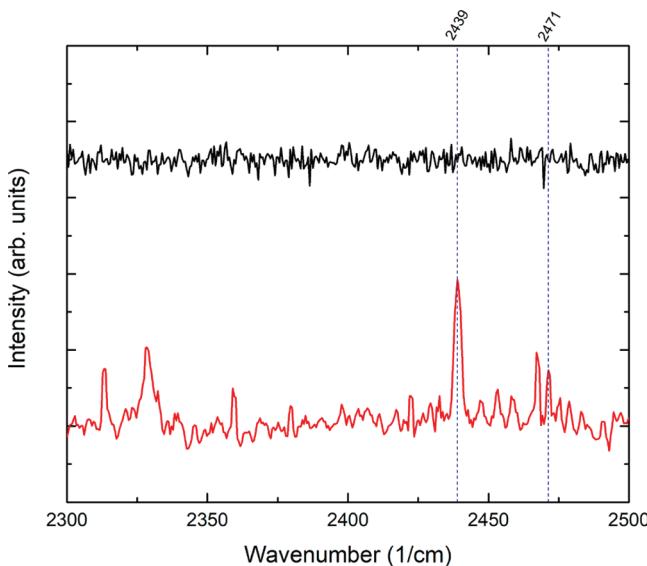


Figure 5. Raman spectra of unbrominated (black) and brominated (red) samples from 2300 to 2500 cm^{-1} . The sloped background was removed for the brominated sample.

the unbrominated sample shows minimal activity, two sets of Raman-active peaks are shown in the brominated sample at 2438 cm^{-1} . Apreyan et al. reports Raman-active peaks at $\sim 2439\text{ cm}^{-1}$ to be bromic acid (HBr).²⁸

After Raman analysis, further compositional analysis was done using energy-dispersive X-ray spectroscopy (EDS). This poses a particular challenge, as EDS software commonly misidentifies bromine and aluminum, because of their close characteristic energies, $\text{BrK}\alpha$ at 1.480 keV and $\text{AlK}\alpha$ at 1.487 keV , respectively.²⁹ In our sample, the substrate contains aluminum, which will muddle the relative concentrations of each element. For this reason, only the higher-energy $\text{BrK}\alpha$ at 11.907 keV is reliable for element identification. The resulting spectra can be found in Figure 6, which depicts the higher-energy spectra with an inset showing a small, but present, bromine $\text{K}\alpha$ peak. With this analysis, we can confirm the formation of bromine products on the surface.

Finally, to test the viability in application, we completed resistance-temperature (RT) measurements on the same sample before and after bromination that share similar electrical properties, as shown in Figure 7. Figure 5a shows a plot of resistance versus temperature for both the unbrominated YBCO and the brominated YBCO samples, as well as the same brominated YBCO sample measured 8 days after storage in air. As seen in the graph, there is good agreement between the cooling experiment and the following warming experiment. It should be noted that noise arising from contacts was eliminated in the warming experiment of the unbrominated sample. Additional characterization of the film arises

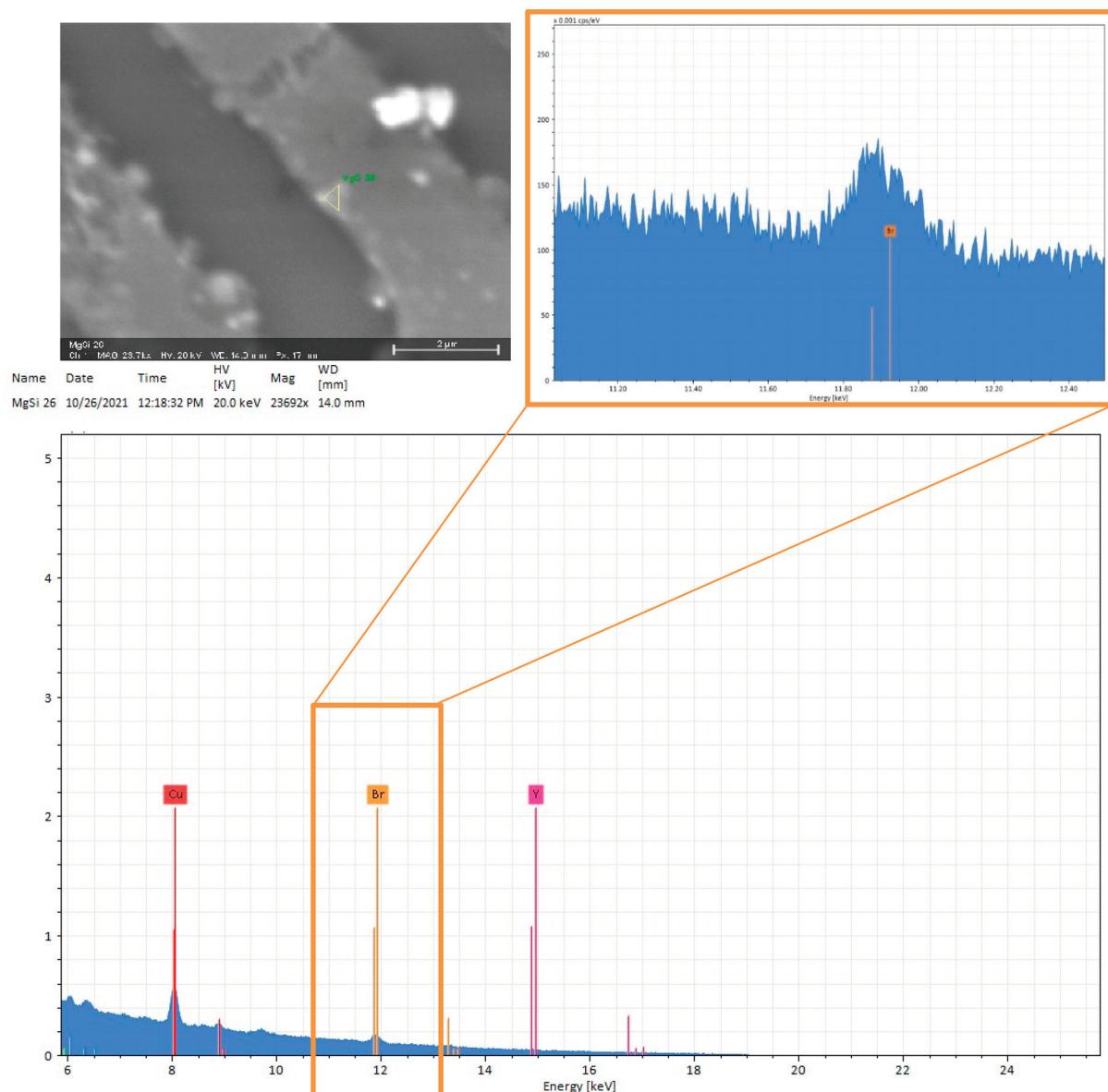


Figure 6. EDS spectra in the high-energy (6–24 keV) range. The inset shows the BrK α peak.

from the patterned YBCO surface, which allows for precise electrical measurements.

Additionally, as the bromine etches only the surface of the film, the electrical thickness of the brominated sample after the reaction can be found via mathematical calculation. The starting films were commercially purchased to be 50 nm thick, giving a resistivity calculation of 892.6 $\mu\Omega/\text{cm}$ using the following calculation:

$$\rho_{290K} = \frac{Rtw}{L}$$

Where ρ is the resistivity in $\mu\Omega/\text{cm}$, R is the resistance at 290 K, t is the thickness of the film, w is the width of the channel, and L is the length of the channel. Using this relationship, we can calculate a new film thickness by assuming that the resistivity has not changed after treatment. Using the brominated film resistance at 290 K, the bromination reaction (1% Br in ethanol for 5 s) was found to poison the surface at 3 nm deep, leaving an effective electrical thickness of \sim 47 nm.

Figure 7b shows the first derivative of the resistance from Figure 7a. From this manipulation, the T_c can be determined by the center of the peak. It can be seen that there are small differences in T_c between the unbrominated and brominated samples, with the brominated samples having a slightly lower critical temperature at 86.5 and 86.4 K, respectively. The brominated sample has a T_c of 86 K 1 week after bromination, indicating slight degradation of the thin film.

The literature reports several reaction products, namely, CuBr, CuBr₂, YBr₃, and YBrO₃ complexes. The AFM and HIM images show a distinct change in the YBCO surface before and after bromination, with several crystalline species forming on the surface. Although Vasquez et al. shows the possibility of both CuBr and CuBr₂ species forming after the bromination reaction, no evidence of CuBr peaks were found. However, there is the possibility of CuBr₂ formation, which has been characterized in this study by Raman spectroscopy with a forming in the brominated sample at \sim 188 nm. Additionally, the rhombic structures appearing on the YBCO surface could be evidence of a monoclinic unit cell structure, which CuBr₂

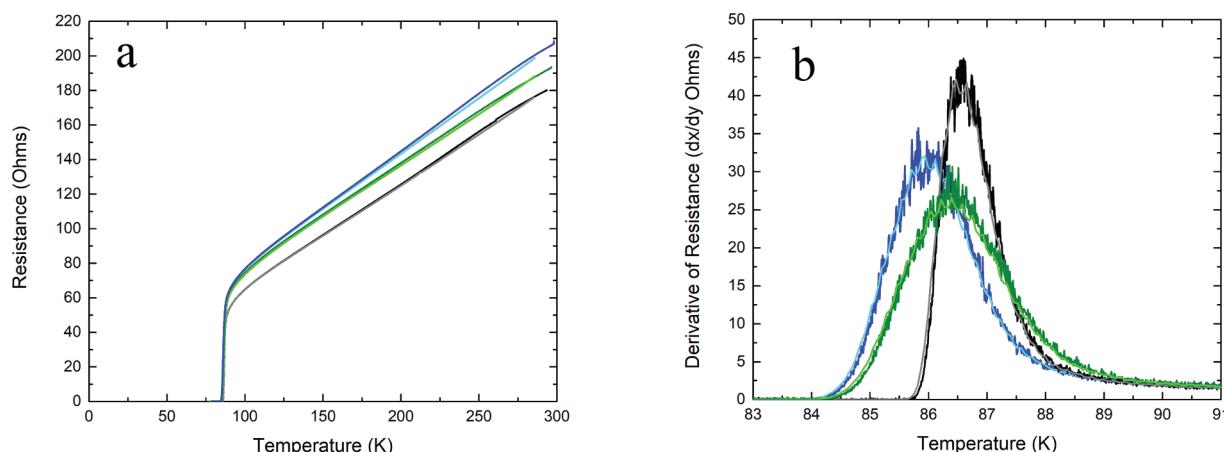


Figure 7. Electronic properties of a patterned YBCO sample before (black), immediately after the bromination reaction (green), and measured again 8 days after bromination (blue). (a) RT measurements, with slight variations in the starting resistances. (b) First derivative of the RT measurements in panel a. The darker lines represent the data taken from the cooling measurement ($T \rightarrow 77$ K), and the lighter colors represent that from the warming measurement.

has and CuBr does not (monoclinic versus cubic, respectively), but this speculation is qualitative. Combined, this data suggests that the bromine reacts with YBCO to form Cu^{2+} products, not Cu^{1+} products as postulated in the Vasquez et al. study. Further characterization such as compositional surface analysis is needed.

Additionally, although the Vasquez et al. and the Mukhopadhyay and Wei studies both showed evidence of the formation of YBr_3 after bromine etching, no Raman peaks could be identified against existing literature for this compound in this study. However, the YBrO_3 complexes postulated to be on the surface by XPS in previous studies have not yet been recorded via Raman spectroscopy and cannot be identified. As with the formation of the copper products, additional compositional surface analysis will be necessary to confirm surface species. Our results are consistent with the previous literature positing bromine as a nanocluster of copper and oxygen lattice fragments, but we are unable to exclude the existence of YBrO_3 compounds.

For electrical characterization, geometrically precise measurements were completed comparing unbrominated and brominated YBCO surfaces for the first time. Here, we found that lingering etchant products on the surface have a minimal impact on the performance of thin films. We conclude that these products should not impact the performance of thin films that are used in devices such as JJs and may serve as a possible means of facile processing that is easily integrated into device fabrication.

The summary of this study is as follows: Thin films of patterned YBCO were etched in dilute bromine-ethanol solution in an investigation for the deterioration of electronic performance with respect to nanoscale devices. Lingering reaction products on the surface are postulated to be CuBr_2 and possibly copper or yttrium bromine oxide complexes. Additionally, the bromination of the surface results in minor changes to the electrical properties of YBCO and leaves bromine processing as an avenue to explore for etching nanoscale films for HTS devices. Further work on this project may integrate this process into the fabrication of nanoscale electronic devices such as JJs and, ultimately, superconducting quantum interference devices (SQUIDS). It is necessary for

further research to measure the impacts of such treatment on device performance.

■ ASSOCIATED CONTENT

● Supporting Information

The Supporting Information is available free of charge at <https://pubs.acs.org/doi/10.1021/acsanm.1c03098>.

Additional experimental details, materials, and methods ([PDF](#))

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Notes

The authors declare no competing financial interest.

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ABBREVIATIONS

HTS, high-temperature superconductor
YBCO, yttrium–barium–copper oxide
HIM, helium ion microscope
EDS, energy-dispersive X-ray spectroscopy
AFM, atomic force microscopy
RT, resistance–temperature
 T_c , critical temperature
JJ, Josephson junction
FIB, focused ion beam
FOV, field of view

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